

**METHOD AND SYSTEM FOR PRODUCING
A GAS-SENSITIVE SUBSTRATE**

ABSTRACT OF THE DISCLOSURE

A method includes forming a gas-sensitive substrate (102, 102a-102c) during a production process by dispensing (708) one or more gas-sensitive materials onto the substrate and drying (712) the one or more gas-sensitive materials on the substrate. The method also includes adjusting (720) the production process based on one or more sensor measurements associated with the substrate and/or the production process. Adjusting the production process could include conditioning (706, 710, 716) air around the substrate so that the conditioned air has one or more specified characteristics and adjusting (720) the one or more specified characteristics based on the one or more sensor measurements. The one or more sensor measurements could include one or more measurements of a moisture content of the substrate. Adjusting the production process could also include adjusting (720) a tension of the substrate. The one or more gas-sensitive materials could be deposited in multiple regions (202-206, 302-306, 402-408, 510a-510d) of the substrate, such as along multiple tracks extending lengthwise down the substrate.

Figure 1